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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Applicant: **Kwan, et al.**

Case: **4209**

Serial No.: **09/494,327**

Filed: **January 28, 2000**

Examiner: **Markoff, Alexander**

Group Art Unit: **1746**

Title: **METHOD AND APPARATUS FOR CLEANING A SEMICONDUCTOR
WAFER PROCESSING SYSTEM**

COMMISSIONER FOR PATENTS
Washington, DC 20231

Attention: Official Draftsman

S I R:

SUBMISSION OF FORMAL DRAWINGS

The Applicants submit herewith 2 sheets of formal drawings (FIGS. 1 through 2) in connection with the above-captioned application.

Respectfully submitted,

Mar 27, 2003

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I hereby certify that this correspondence is being deposited on March 27, 2003 with the United States Postal Service as first-class mail, with sufficient postage, in an envelope addressed to the Commissioner for Patents, Washington, DC 20231.

Allyson M. DeVesty
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